

ABSTRACT

A process and an apparatus for treating and recovering an CVD exhaust gas is provided, which can reduce periodical maintenance by converting the raw gas employed and the intermediate products contained in the CVD system into highly volatile halides, separating and recovering them as materials with good reusability. An unreacted raw gas and intermediate products contained in CVD exhaust gas are partially decomposed by being subject to decomposition treatment or conversion reaction treatment, and then halogecosilane gas and hydrogen chloride are separated and recovered. Alternatively, a raw gas and intermediate products are decomposed into hydrogen chloride and recovered.

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